

ACKNOWLEDGEMENT RECEIPT

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Title of Invention

A METHOD FOR SUPERCRITICAL CARBON DIOXIDE PROCESSING OF FLUORO-CARBON FILMS

Submission Type : Information Disclosure
Statement

Application Number:

10/711649



EFS ID:

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First Named Applicant: Kohei Kawamura

Attorney Docket Number: SSIT-114

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSIT-114SuppIDS-usidst.xml	6577	2005-05-27
us-ids	us-ids.dtd	7763	2005-05-27
us-ids	us-ids.xml	12026	2005-05-27
package-data	SSIT-114SuppIDS-pkda.xml	1760	2005-05-27
package-data	package-data.dtd	27025	2005-05-27
package-data	us-package-data.xml	19263	2005-05-27
Total files size		74414	

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